Article Storage Facility and Article Transport Facility

ABSTRACT

An article storage facility includes a storage rack configured to store a semiconductor wafer and a reticle, and a storage and retrieval transport apparatus. The storage rack includes a first accommodation unit configured to store a wafer container for containing the semiconductor wafer, and a second accommodation unit configured to store a reticle container for containing the reticle. The storage and retrieval transport apparatus includes a holding unit configured to hold a top flange formed at an upper portion of the wafer container to support the wafer container in a hanging state. A flange portion configured to allow the storage and retrieval transport apparatus to hold the reticle container using the holding unit to support the reticle container in a hanging state is formed at an upper portion of the reticle container.

[Fig.4]